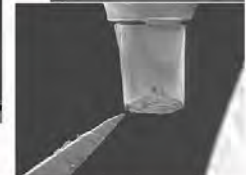
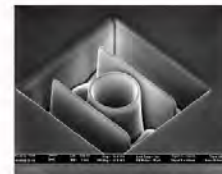
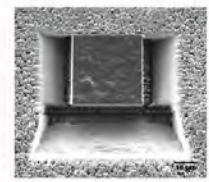
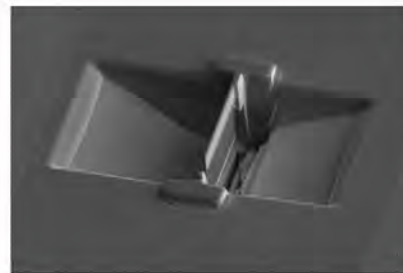


Frontiers in Microscopy & Microanalysis

FIB/SEM Scios: High resolution & throughput for 2D and 3D analytical characterization



Talk by: Dr. Brandon Van Leer from FEI, USA Monday 11th of July 2016 - 10:00 to 11:30am AIBN #75; Level 4 Seminar Room

Over the past 20 years, focused ion beam (FIB) and SEM/FIB instrumentation has transformed scientists' ability to investigate materials to develop new sample preparation methods to becoming the industry standard and "work-horse" for site-specific cross-section analysis, S/TEM sample preparation (cross-section or plan view) and nanoscale patterning/prototyping applications.

The Scios DualBeam offers proven FIB technology for FIB nanotomography and sample preparation. With the assistance of the EasyLift manipulator, high-quality, ultra-thin S/TEM samples can be prepared at site specific locations in 1 - 2 hours. Scios' advanced Trinity detection technology provide simultaneous acquisition of SE and BSE information at low SEM voltages for superior contrast.